



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Patent Application of:

Koichiro TANAKA

Serial No. 10/827,402

Filed: April 20, 2004

For: BEAM IRRADIATION APPARATUS,
BEAM IRRADIATION METHOD, AND
METHOD FOR MANUFACTURING
THIN FILM TRANSISTOR

) Group Art Unit: 2891

) Examiner: Bradley Smith

) CERTIFICATE OF MAILING
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Alexandria, VA 22313-1450, on November 9,
2006.

) Adrian Stampfer

AMENDMENT

Honorable Commissioner of Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Official Action dated August 9, 2006, please consider the following amendments and remarks in connection with the above-identified application.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 7 of this paper.